

INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Attorney Docket Number	4641-61273
	Application Number	10/000,458
	Filing Date	November 30, 2001
	First Named Inventor	Yahiro
	Art Unit	2881
	Examiner Name	Mary A. El Shammaa

U.S. PATENT DOCUMENTS

Examiner's Initials*	Cite No. (optional)	Number	Date	Name
ME		6,059,981	9-May-2000	Nakasuji
ME		5,396,077	7-Mar-1995	Sohda et al.

FOREIGN PATENT DOCUMENTS

Examiner's Initials*	Cite No. (optional)	Number	Date	Country
ME		P2001-203149A	27-Jul-2001	Japan

OTHER DOCUMENTS

Examiner's Initials*	Cite No. (optional)	
ME		"New imaging and deflection concept for probe-forming microfabrication systems", by H.C. Pfeiffer, J. Vac. Sci. Technol., Vol 12, No. 8, Nov./Dec. 1975, pages 1170-1173

EXAMINER SIGNATURE: ME El Shammaa	DATE CONSIDERED: 11.12.03
* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.	